



RESPONSE UNDER 37 CFR 1.116  
EXPEDITED PROCEDURE  
EXAMINING GROUP 2851

00862.022434.

PATENT APPLICATION

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:

Shinichi SHIMA

Application No.: 09/986,958

Filed: November 13, 2001

For: EXPOSURE APPARATUS, METHOD OF  
MANUFACTURING SEMICONDUCTOR  
DEVICES, SEMICONDUCTOR MANUFACTURING)  
PLANT, METHOD OF MAINTAINING EXPOSURE :  
APPARATUS, AND POSITION DETECTOR )

)  
: Examiner: H. Nguyen  
)  
: Group Art Unit: 2851  
)  
: Confirmation No.: 638  
)  
: October 10, 2003

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Commissioner for Patents

P.O. Box 1450

Alexandria, VA 22313-1450

AMENDMENT AFTER FINAL REJECTION AND LETTER  
FORWARDING SUBSTITUTE SPECIFICATION

Sir:

In response to the Official Action dated July 11, 2003, please amend the above-identified application as follows: